

Effect of growth conditions on defect incorporation and optical efficiency of AlGaN/GaN multi-quantum wells

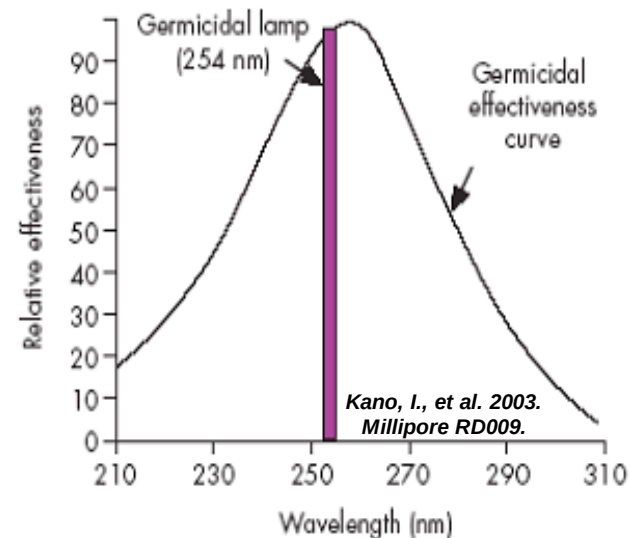
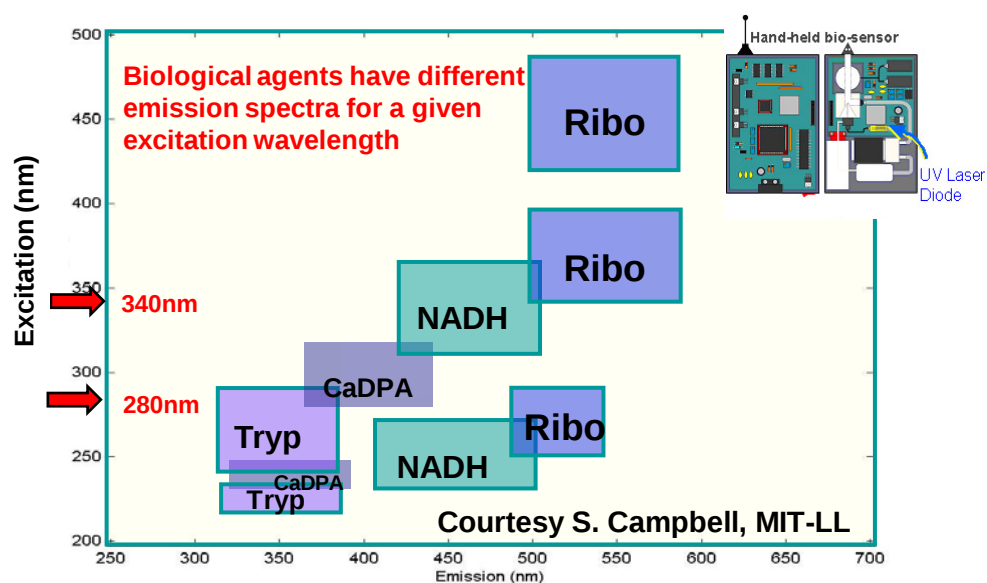
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Motivation for compact UV emitters

Development of miniaturized UV optical sources for:

- Biological agent detection systems via UV-L(ED)IF
- Decontamination and water purification



Decontamination by UV radiation

- AlGaN-based UV emitters for portable biosensing
 - Laser- or LED-induced fluorescent bioagent detection
- Ongoing challenges:
 - Improve output power
 - Minimize DL for efficient detection

AlGaN/GaN MQW growth conditions

Temp (T_g): 1010 – 1065 °C

Pressure: 75 torr

Sources: TMAI, TMGa, NH_3 , H_2

V/III Ratio: $1000 < \text{V/III} < 4000$

Sapphire: 0.2° off toward m-plane

340 nm MQW

3000 Å $\text{Al}_{0.3}\text{Ga}_{0.7}\text{N}$

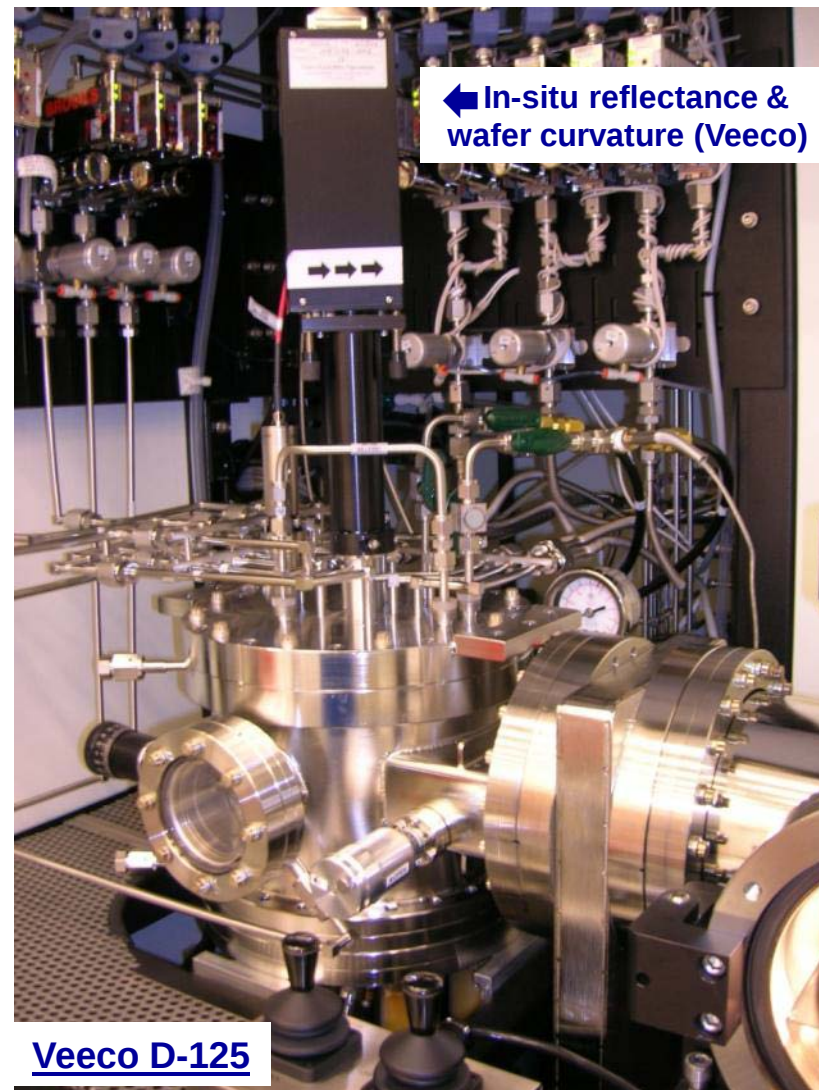
6x $\text{Al}_{0.2}\text{Ga}_{0.8}\text{N}/\text{GaN}$ MQW

75 Å $\text{Al}_{0.2}\text{Ga}_{0.8}\text{N}$

3.6 μm $\text{Al}_{0.3}\text{Ga}_{0.7}\text{N}$
TDD $\sim 5\text{e}9 \text{ cm}^{-8}$

1.9 μm AlN

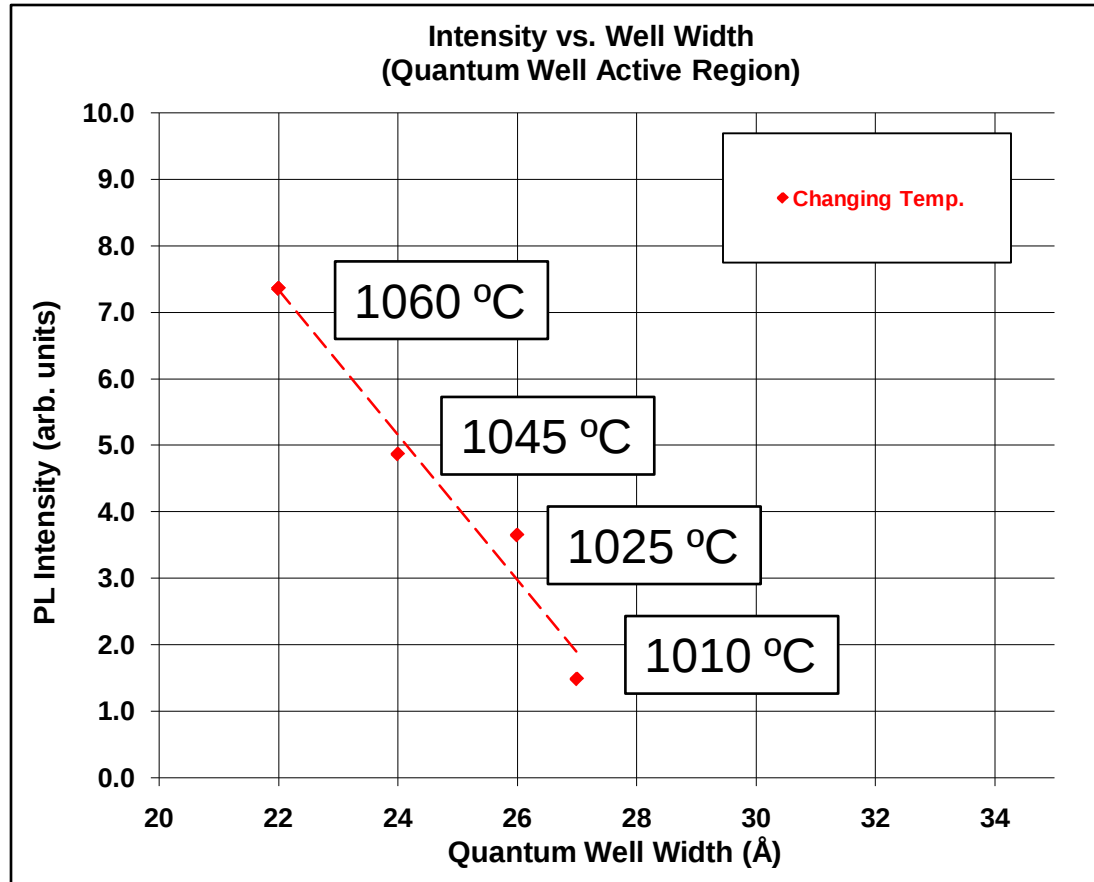
Sapphire





Impact of well growth temperature (T_g)

340 nm MQW

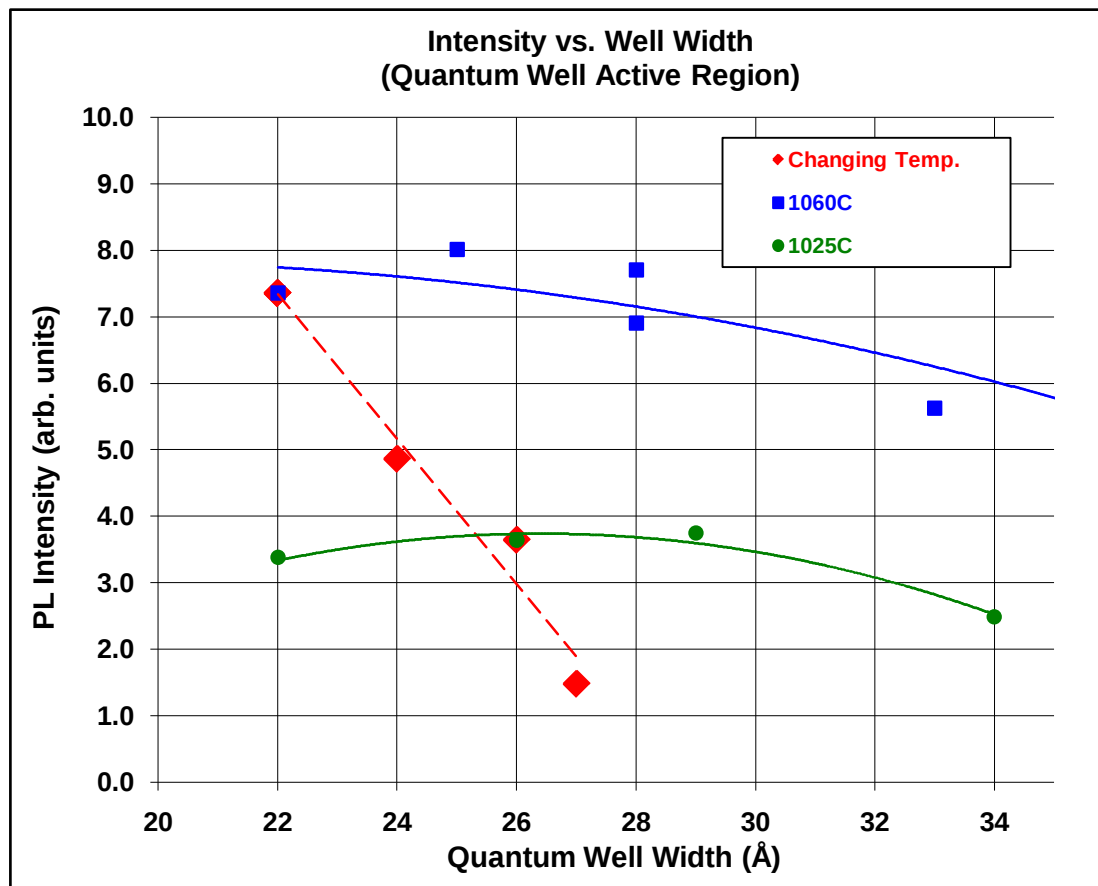


- 5X PL intensity for greater QW T_g



Impact of well growth temperature (T_g)

340 nm MQW

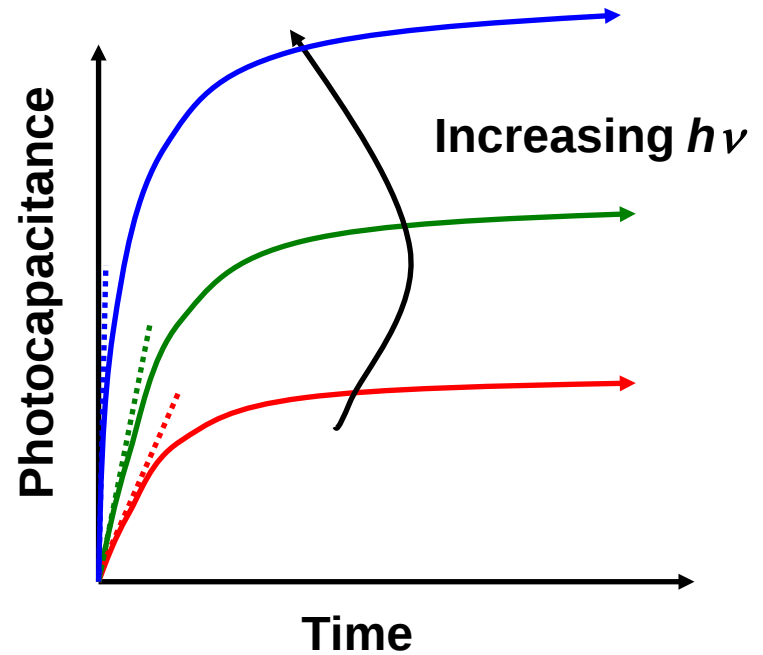
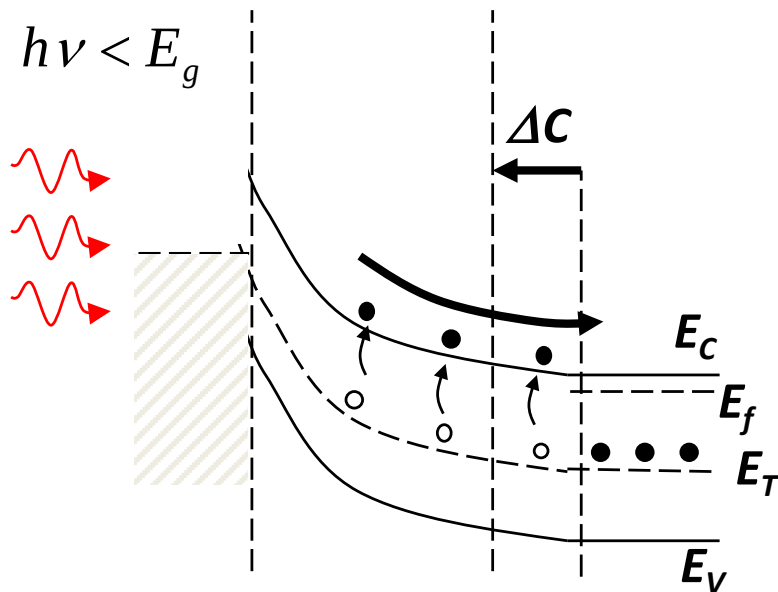


- PL improvement with greater T_g not QCSE
- Reduced PL for lower T_g due to excess point defects?

DLOS background

Deep Level Optical Spectroscopy (DLOS)¹

- Photocapacitance technique
- Sub-band gap optical stimulation to photoionize defect levels (reverse of PL)
- Quantify non-radiative defect level energy and density (difficult for PL)



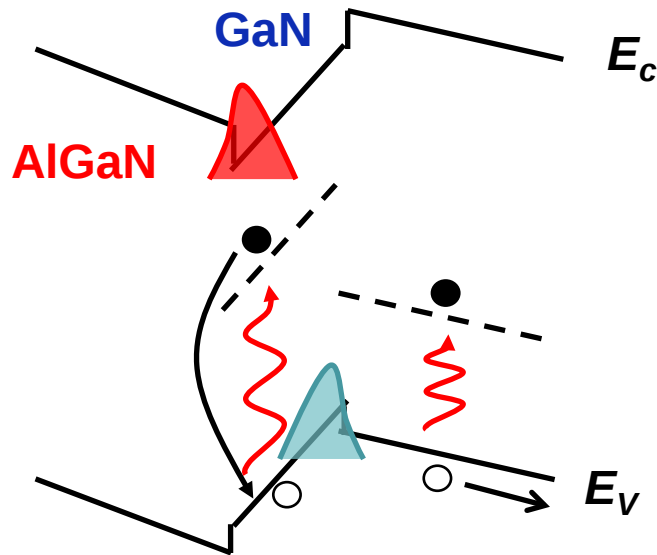
- DLOS only sensitive to depleted regions
- Enables nano-scale depth resolution

- Optical cross-section $\sigma^o = e^o / \Phi(h\nu)$
 - $dC(t)/dt|_{t=0} \propto \sigma^o(h\nu)$
- Optical ionization energy E^o
- Defect density D_t from light

1. Chantre et al. PRB 23, 5335 (1981).

Depth-resolved DLOS

AlGaN/GaN QW

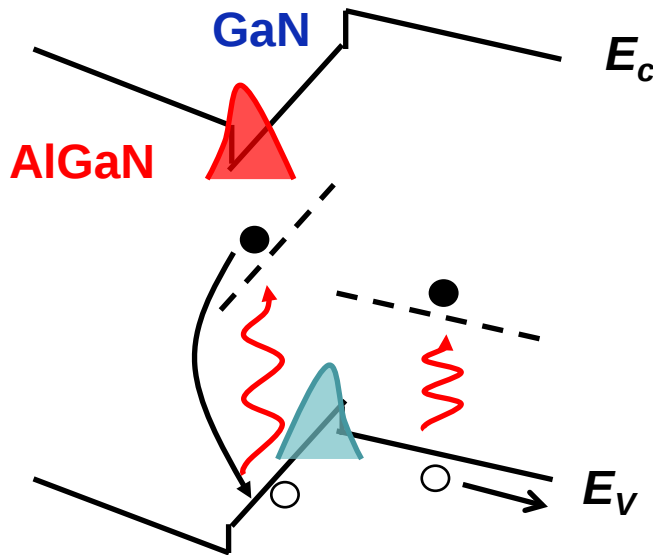


Not sensitive to well defects

- Slow growth rates and strain prohibit extending well region into thin film

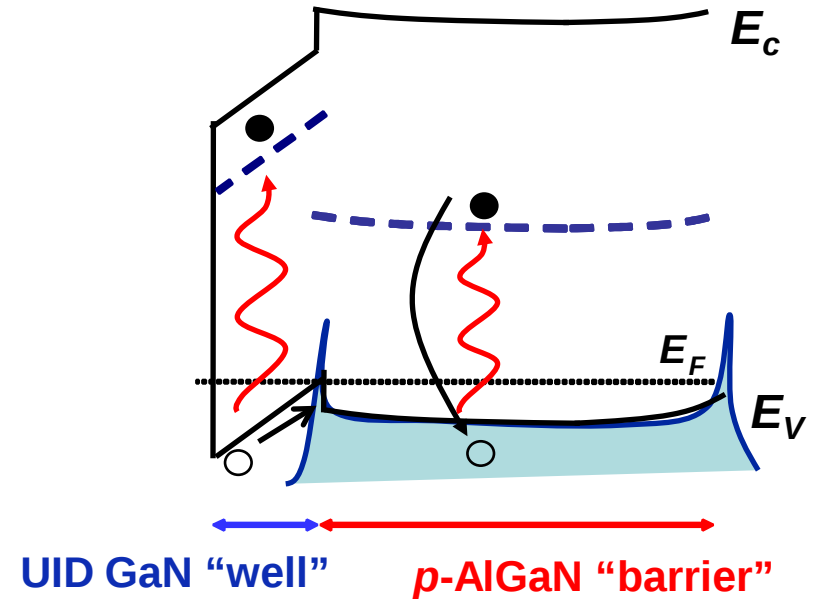
Depth-resolved DLOS

AlGaN/GaN QW



Not sensitive to well defects

“half QW”



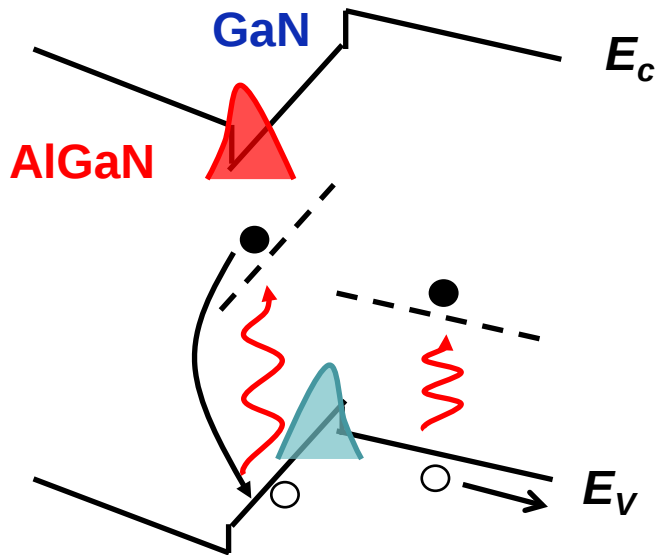
Mainly sensitive to “well” defects

Difficult to implement:

- Polarization requires p-type AlGaN template for “half QW”

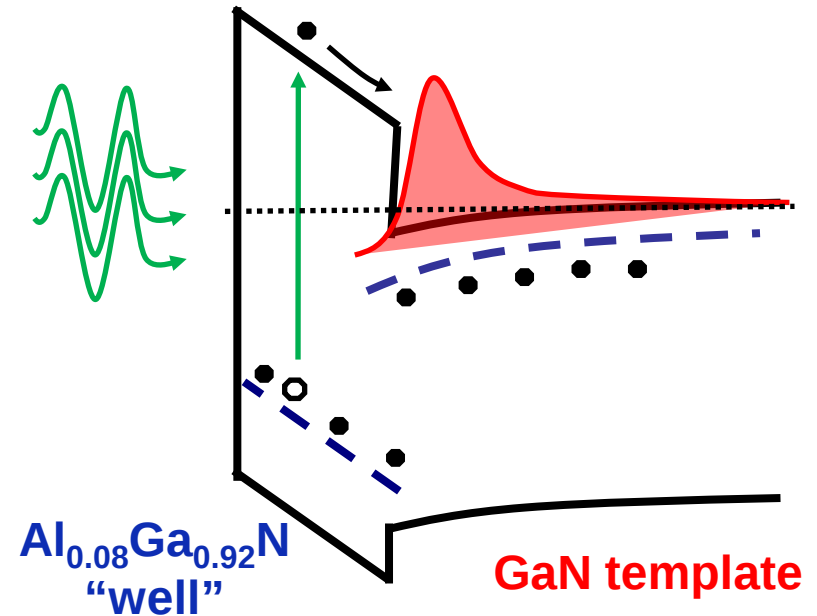
Depth-resolved DLOS

AlGaN/GaN QW



Not sensitive to well defects

"half QW"



Mainly sensitive to "well" defects

- Nominal QW growth conditions for dilute AlGaN cap
- Expect defect incorporation similar to MQW active region

DLOS sample structure

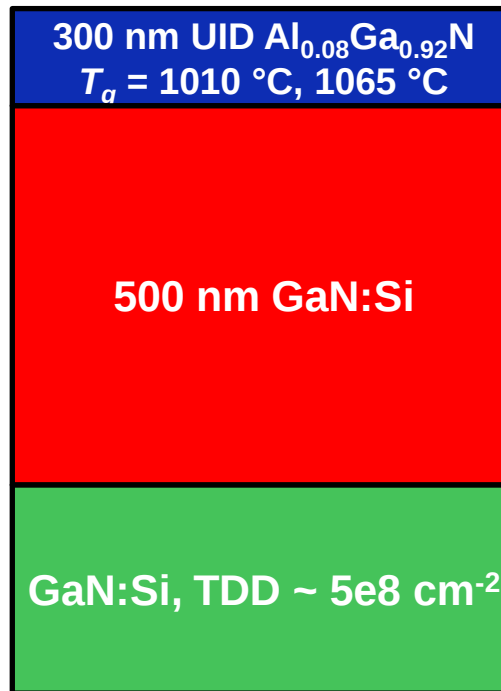
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Pressure: 75 torr

Sources: TMAI, TMGa, NH_3 , H_2

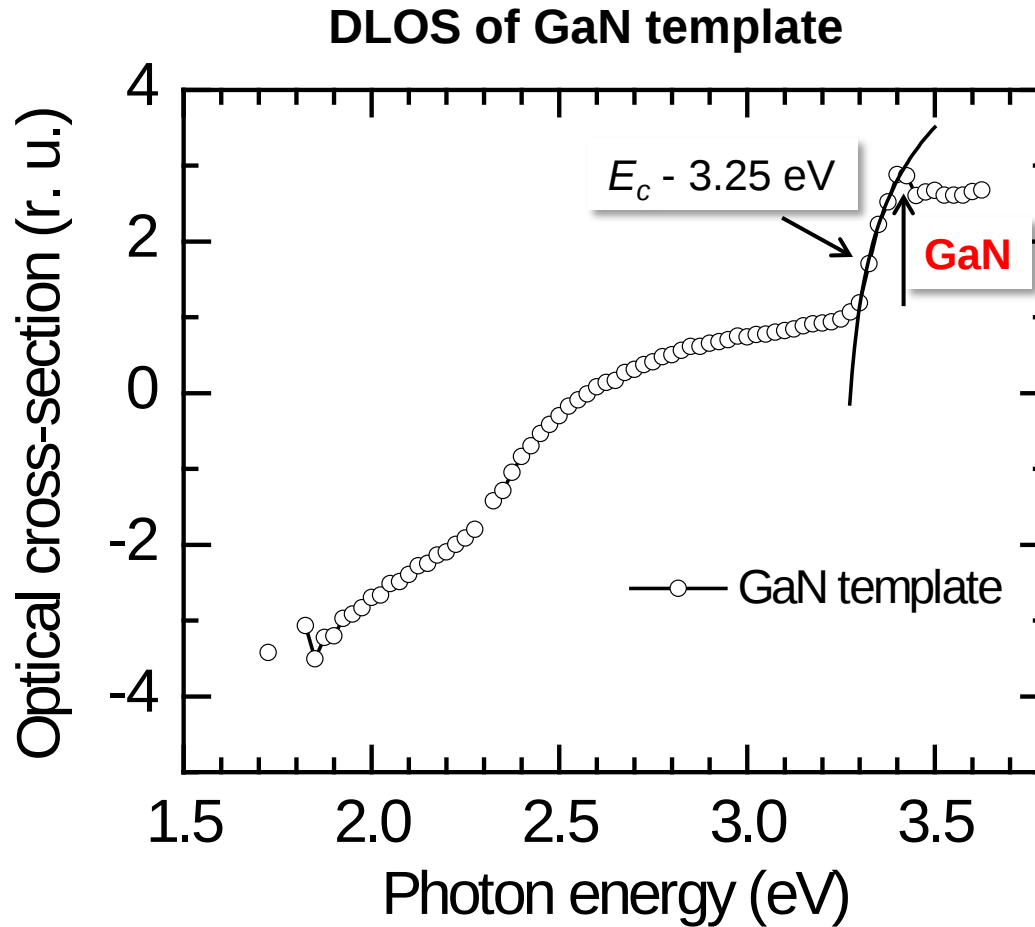
V/III Ratio: $1000 < \text{V/III} < 4000$

Sapphire: 0.2° off toward m-plane



- QW growth conditions
- Coherently-strained

DLOS for QW growth conditions

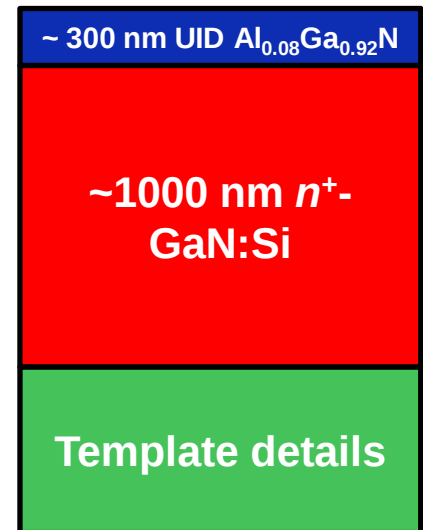
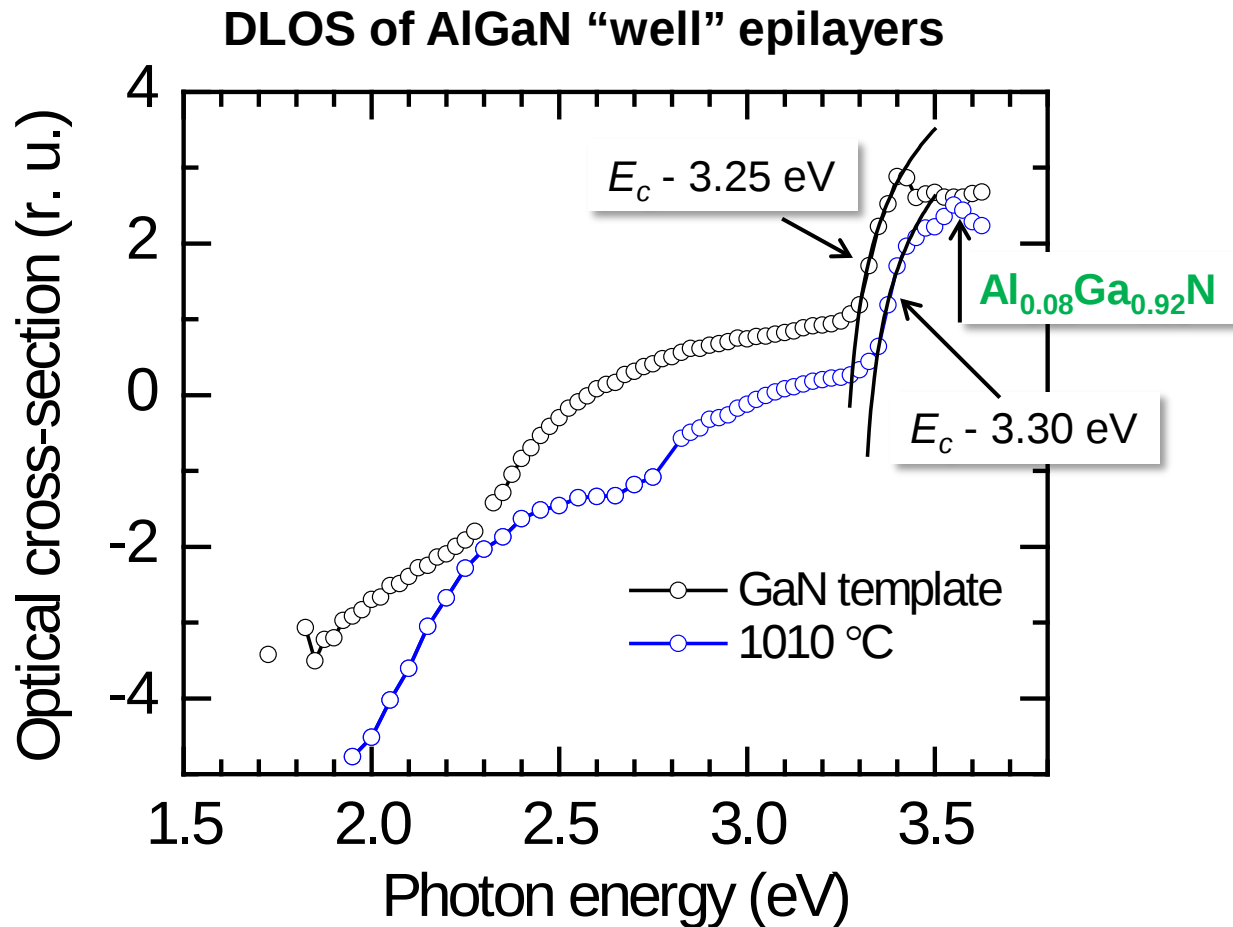


~1000 nm n^+ -
GaN:Si

Template details

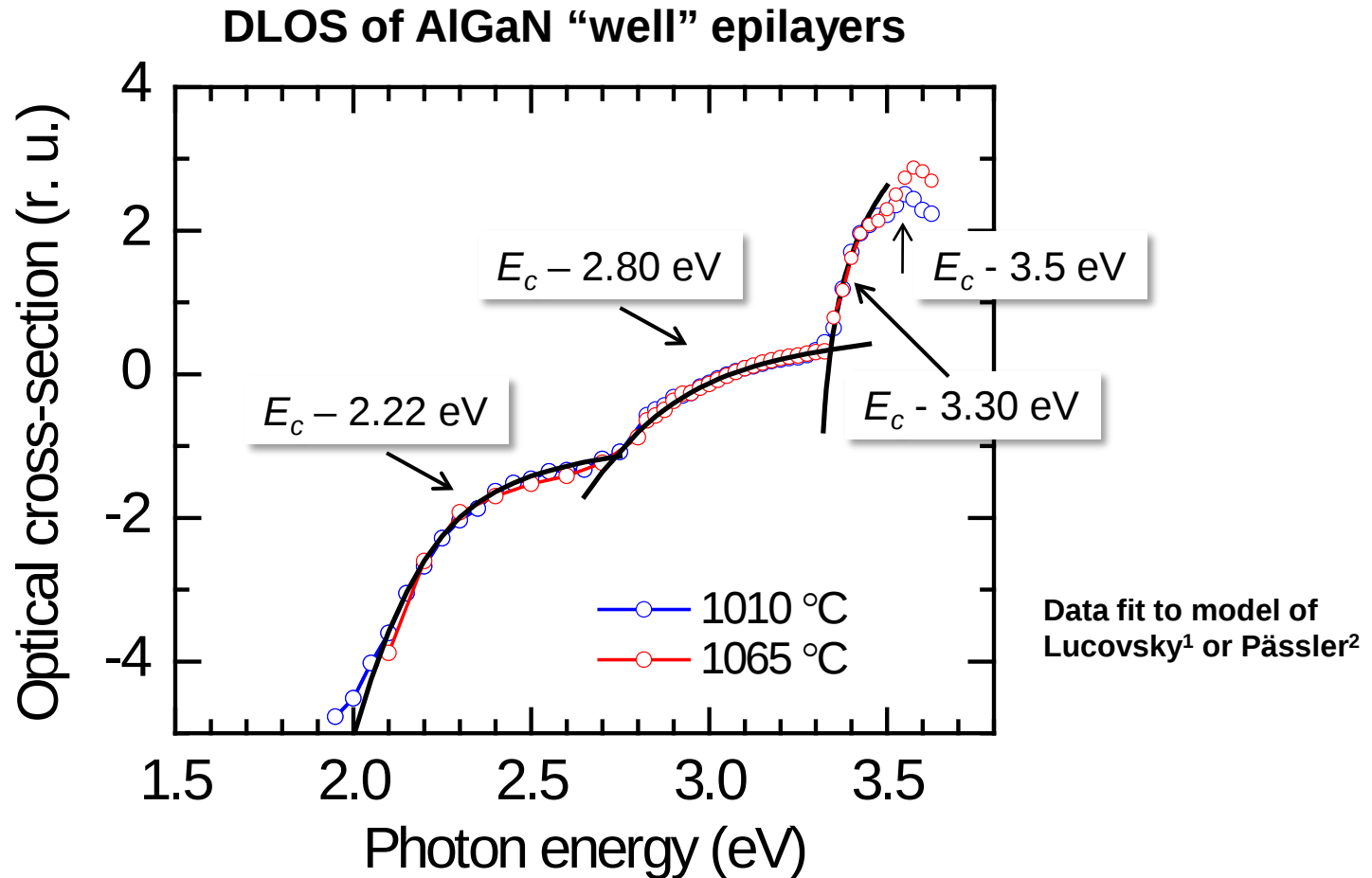
GaN template not associated with AlGaN/GaN QWs

DLOS for QW growth conditions



Different deep level spectra with “well” epilayer

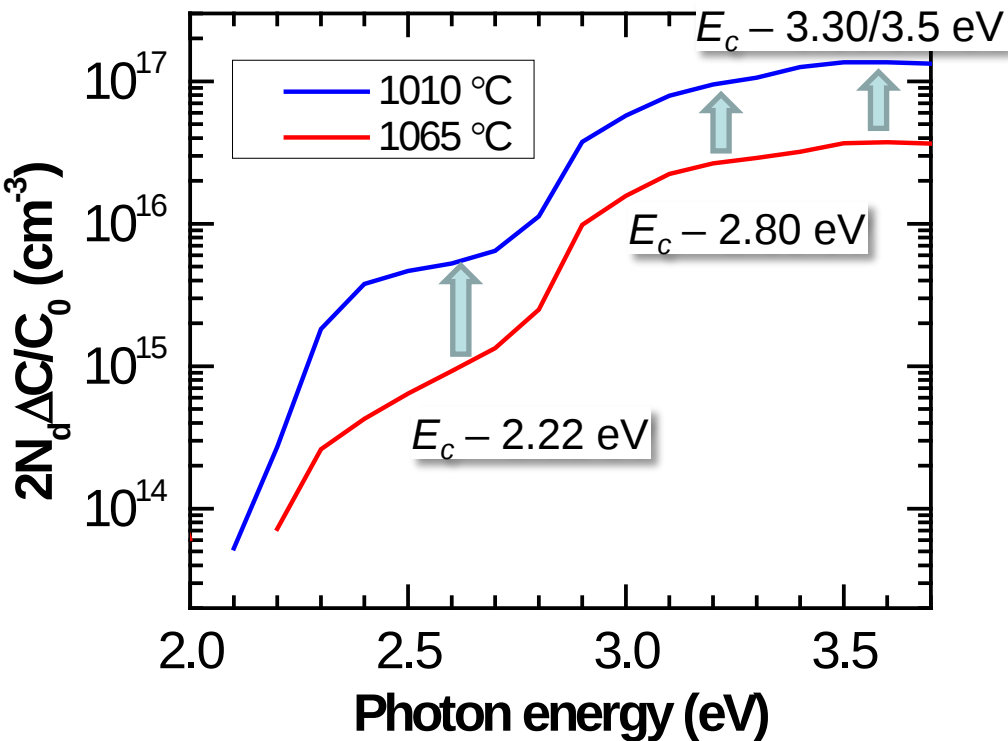
DLOS for QW growth conditions



- Same QW deep levels for both T_g
- Changing T_g by 55 °C did not introduce new defect levels

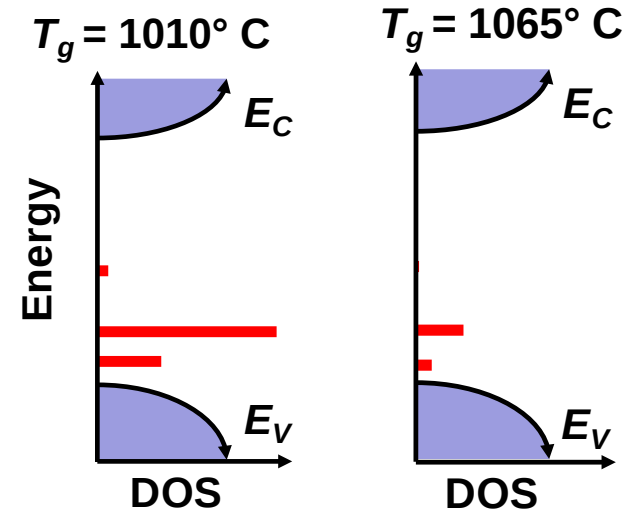
Defect density vs. QW T_g

Steady-state Photocap.



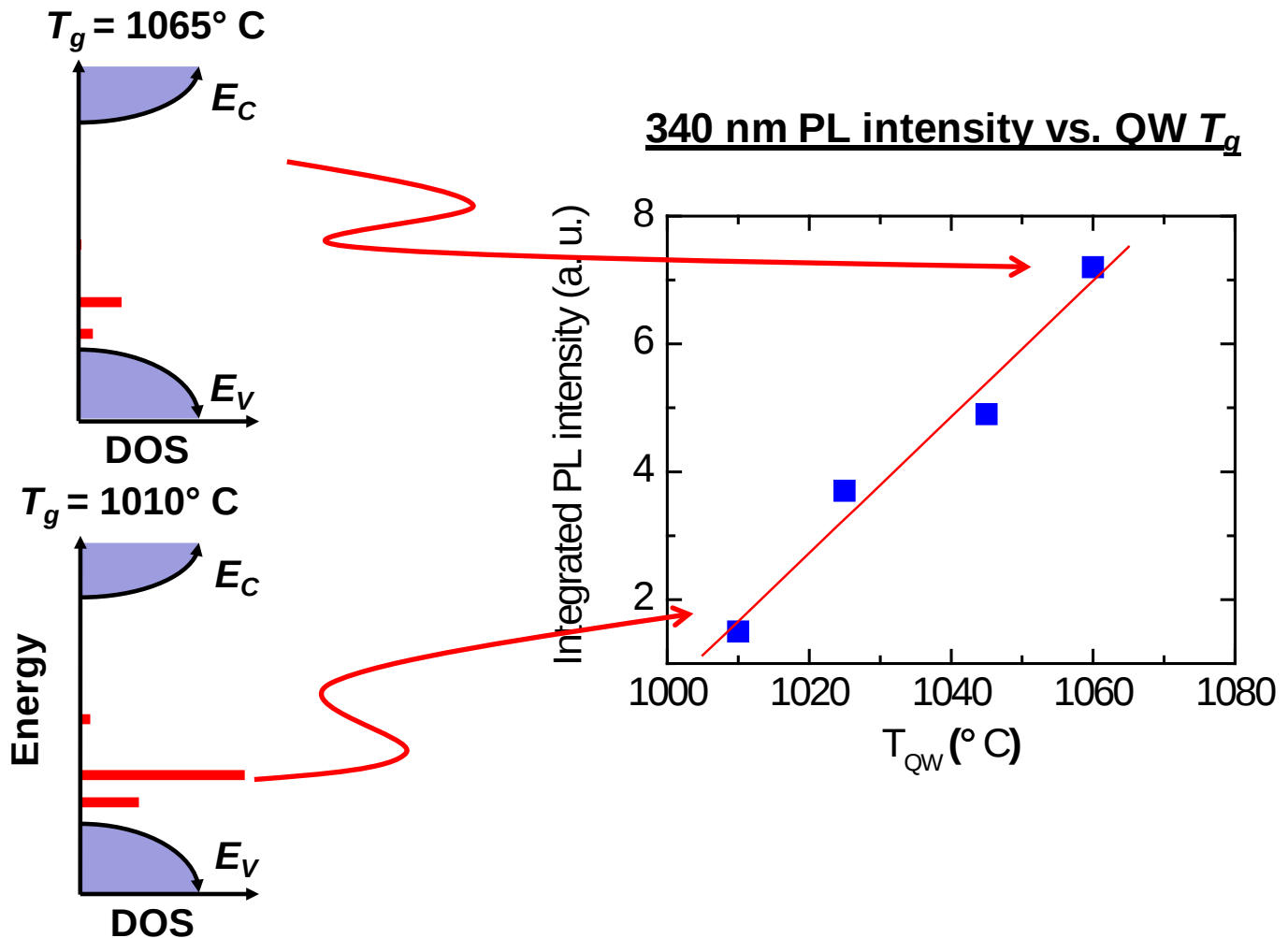
Defect density (cm^{-3}) vs. T_g

Level (eV)	$T_g = 1010^\circ\text{C}$	$T_g = 1065^\circ\text{C}$	Δ
2.20	6.5×10^{15}	1.3×10^{15}	5X
2.80	10×10^{16}	2.8×10^{16}	3.6X
3.30/3.50	3.6×10^{16}	8.3×10^{15}	4.3X



- $>3\times$ increase in defect density for lower T_g
- $[E_c - 2.80 \text{ eV}]$ least sensitive to T_g
 - Still likely dominate non-radiative recombination center

Summary and Conclusions



- Used DLOS and PL to study impact of QW defects on AlGaIn/GaN MQW efficiency
- Increasing QW T_g improves PL intensity and reduces point defect density
- Controlling deep level defect incorporation critical for highly efficient UV emitters